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Sheet	1	of	1

COMPLETE IF KNOWN	
Application Number	09/651,779
Confirmation Number	2448
Filing Date	August 30, 2000
First Named Inventor	Scott E. Moore
Group Art Unit	3723
Examiner Name	Dung V. Nguyen
Attorney Docket No.	108298515US

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent or Application NUMBER	Kind Code (if known)	Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
DVN	AA	U.S. Patent Application Publication No. US 2002/0025763 A1		Lee et al.	02/28/2002	
	AB	U.S. Patent Application Publication No. US 2002/0025759 A1		Lee et al.	02/28/2002	
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Examiner Initials*	Cite No.	Foreign Patent or Application Office	NUMBER	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T
DVN	AG	KONDO, S. et al., "Abrasive-Free Polishing for Copper Damascene Interconnection," *Journal of the Electrochemical Society*, Vol. 147, No. 10, pp. 3907-3913, The Electrochemical Society, Inc., Pennington, New Jersey, 2000.	
DVN	AH	McGraw-Hill, *Concise Encyclopedia of Science & Technology*, Sybil P. Parker, Editor in Chief, Fourth Edition, p. 367, McGraw-Hill, New York, New York, 1998.	

EXAMINER	DATE CONSIDERED
Dung Van Nguyen	4-21-2003

*EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application(s).